

## Project Overview

- BioMEMS microchannels**
  - fabricate microchannels in various materials with electrodes in channels
  - explore effects of channel geometry and material on fluid flow
- Microfluidics packaging design**
  - design mechanism for leak-tight sealing of microchannels
  - design input/output methods
- Packaged microfluidics testing**
  - test packaging designs at various stages
  - measure fluid flow rates and electrical properties of connections
  - improve leak-tightness of design
  - use packaged microfluidics for future biofunctionalization of surfaces

## Microfluidics Packaging Design

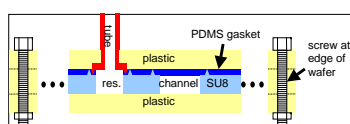
### Packaging Requirements:

- **leak-tight sealing** → gasket clamping mechanism SU-8 or PDMS bonding
- **transparency** → plastic or Pyrex wafer plastic packaging plate exposed wafer
- **inlet/outlet fittings** → flanged microtubing threaded fittings
- **accessible electrodes** → smaller cover plate spring-loaded electrodes

### Longer-term Goals:

- 4 of 4 requirements met
- on-chip micropumps and microvalves
- individual channel and electrode addressing
- controllable apertures for vacuum sensing
- extremely robust design for leak-tightness
- on-chip integration of optical investigation techniques (e.g., interferometry, waveguides)

## Packaging Design Stages

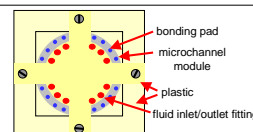
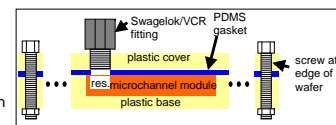


### Stage 1 (initial concept):

- 3 of 4 requirements (exposed electrodes?)
- difficult to fabricate
- depends on availability of flanged microtubing

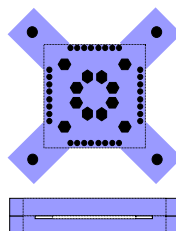
### Stage 2 (modular concept):

- 4 of 4 requirements
- channels/reservoirs milled in plastic – easier to fabricate
- modular design avoids waste
- plastic lid can be tapped, allows for standard Swagelok fittings
- all pumping external



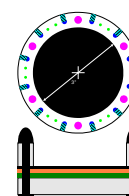
### Stage 3 (X packaging):

- 4 of 4 requirements
- channels patterned on a wafer that drops in to depression in packaging
- modular design avoids waste
- plastic lid tapped for microfluidic fittings
- electrical connections through packaging and via alligator clips
- all pumping external

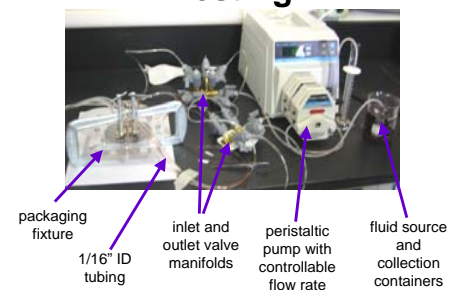


### Stage 4 (ring packaging):

- 4 of 4 requirements
- channels defined on plastic wafer sealed with SU-8 or PDMS bonding
- upper plastic ring holds microfluidic and electrical fittings, clamping screws
- Neoprene gasket for sealing fluid I/Os
- all pumping external



## Packaged Microfluidics Testing



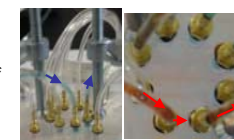
Red color in microfluidic channel shows fluid flowed through

**Stage 3 packaging (with a few modifications) provides leak-tight flow of fluid. Fluid path:**

- inlet container → main inlet tubing → inlet valve manifold → specific inlet tubing → microchannel → specific outlet tubing → outlet valve manifold → main outlet tubing → outlet container



Inlet and outlet fluid containers for flow rate measurement



Successful flow of fluid (blue at left; red at right) through fixture and microchannels. Channel width is 500 microns.

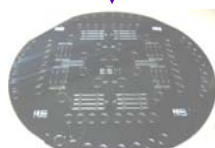
## BioMEMS Microchannels

### Electrode Fabrication

- Begin with bare wafer of desired material (gray).
- Deposit 90Å Cr adhesion layer (green) and 2000Å Au with e-beam evaporation.
- Spin on HMDS primer, then Shipley 1813 photoresist (blue); soft bake.
- Align wafer with electrode mask.
- Expose photoresist to UV light.
- Develop photoresist. (Positive, so exposed areas are removed.)
- Hard-bake photoresist.
- Etch Au and Cr with appropriate etchants and remove resist with acetone.

### SU-8 Mold or Fluid Layer Fabrication

- Spin on SU-8 photoresist (orange) to electrode layer or bare wafer; pre-bake.
- Align wafer with fluid layer or mold mask.
- Expose SU-8 to UV light; post-bake.
- Develop in SU-8 developer. (Neg., so unexposed areas are removed.)



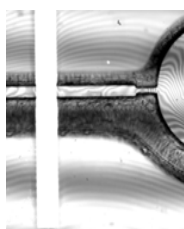
SU-8 master for molding PDMS fluid flow layers

### PDMS Gasket or Fluid Layer Fabrication

- Spin on PDMS (purple) to SU-8 mold wafer.
- Bake in box furnace for 2 h at 70°C.

### PDMS Delamination and Assembly

- Gently loosen edges of cured PDMS with razor blade
- Submerge PDMS wafer in dish of methanol
- Hold one edge of PDMS with tweezers and gently pull from wafer (keeping in methanol as much as possible)
- Remove wafer from dish and allow PDMS to float
- Slide (electrode) wafer to be assembled under PDMS layer in dish
- Coarse align PDMS to wafer while in dish
- Remove wafer and PDMS from dish and align carefully by hand or under microscope, dropping methanol on if sticking occurs, then let dry.



PDMS fluid flow layer aligned and assembled with electrodes patterned on Pyrex substrate

## Conclusions

- Microchannels can be easily fabricated in either SU-8 or PDMS on a variety of substrates (silicon, Pyrex, Kapton, etc.) with or without electrodes.**  
*Future work: expand "toolbox" of microchannel, substrate, and electrode materials for future inexpensive all-polymer devices; explore sealed microchannels.*
- Iterative packaging design has resulted in steady improvements from initial concept to viable fixtures.**  
*Future work: fabricate Stage 4 packaging, apply experience to future packaging stages.*
- Initial testing of packaging fixture reveals leak-tight sealing of microfluidic channels.**  
*Future work: test Stage 4 packaging with sealed microchannels, improve leak-tightness timescale, integrate optical elements (waveguides, reflectivity experiment) into wafer and packaging.*